



GP 1765

#8/A

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Wu et al.

Serial No.: 09/132,876

Filed: August 11, 1998

For: Chemical-Mechanical Polishing Method

Group Art Unit: 1765

Examiner: K. Chen

Docket No.: 252103-2040

**Certificate of Mailing**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail, postage prepaid, in an envelope addressed to: Assistant Commissioner for Patents, Washington D.C. 20231, on January 20, 2000.

Signature

**AMENDMENT AND RESPONSE TO OFFICE ACTION**

Assistant Commissioner of Patents  
and Trademarks  
Washington, D.C. 20231

Sir:

The Office Action mailed November 17, 1999 (Paper No. 3), has been carefully considered. In response thereto please enter the following amendments and consider the following remarks.

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TO 1765 UNIT 1765